

 <p><b>APPLICANT'S ART CITATION</b> (Use several sheets if necessary)</p>		Application 09/915,703		OFGS File No. P/2292-4		<b>RECEIVED</b> NOV 04 2003	
		Applicant Byeung-Joon AHN					
		Filing Date July 26, 2001		Group Art Unit 1762		TECHNOLOGY CENTER R3700	

  

U.S. PATENT DOCUMENTS						
Examiner Initial	Document Number	Date MM-YYYY	Name	Class	Sub-class	Filing Date If Appropriate
	US-					
	US-					
	US-					
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	US-					
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FOREIGN PATENT DOCUMENTS							
	Document Number	Date MM-YYYY	Country	Class	Sub-class	Translation	
						Yes	No
LVC	2000-036414	02-2000	Japan	—	—		X
LVC	11-154610	06-1999	Japan	—	—		X
LVC	11-121234	04-1999	Japan	—	—		X

  

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
LVC	Office Action issued by Japanese Patent Office on July 31, 2003 in prosecution of
	corresponding Japanese Patent Application No. 2001-231073 (untranslated)
LVC	English translation of Abstract for Japanese Patent No. 2000-036414
LVC	English translation of Abstract for Japanese Patent No. 11-154610
LVC	English translation of Abstract for Japanese Patent No. 11-121234
Examiner <i>LVC</i>	Date Considered <i>June 27, 2004</i>

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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